



FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE					AGENT. DOCKET NO. ONX-113/DIV	SERIAL NO. 10/747,875	
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT David Horsley et al.		
					FILING DATE December 29, 2003	GROUP <u>2853</u> 2819	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>Haw</i>	A	5,867,302	2/2/1999	Fleming	359	291	8/7/1997
<i>Haw</i>	B	6,137,941	10/24/2000	Robinson	385	140	9/3/1998
<i>Haw</i>	C	6,296,779	10/2/2001	Clark et al.	216	66	2/22/1999
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
<i>Haw</i>	D	0683414	11/22/1995	Europe	G02B	26/08	YES NO
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>Haw</i>	E	S. Suzuki, K. Sato, S. Ueno, M. Sato, M. Esashi, "Semiconductor Capacitance-Type Accelerometer with PWM Electrostatic Servo Technique," Sensors and Actuators, A21-A23 (1990) pp. 316-319					
<i>Haw</i>	F	B. E. Boser, "Electronics for Micromachined Inertial Sensors", Transducers '97, 1997 International Conference on Solid-State Sensors and Actuators, Chicago, June 16-19, 1997					
<i>Haw</i>	G	E. K. Chan, K. Garikipati, R. W. Dutton, "Characterization of Contact Electromechanics Through Capacitance - Voltage Measurements and Simulations," Journal of Microelectromechanical Systems, Vol. 8, No. 2, June 1999					
<i>Haw</i>	H	C. T. Nguyen, "Micromechanical Signal Processors," Doctoral Dissertation, UC Berkeley, December, 1994					
<i>Haw</i>	I	L. Y. Lin, E. L. Goldstein, R. W. Tkach, "Free-Space Micromachined Optical Switches with Submillisecond Switching Time for Large Scale Optical Cross-Connects, IEEE Photonics Technology Letters, Vol. 10, No. 4, April 1998					
<i>Haw</i>	J	H. Toshiishi, H. Fujita, "Electrostatic Micro Torsion Mirrors for an Optical Switch Matrix," Journal of Microelectromechanical Systems, Vol. 5, No. 4, December 1996.					
<i>Haw</i>	K	A. Selvakumar, K. Najafi, "A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension," Journal of Microelectromechanical Systems, Vol. 7, No. 2, June 1998.					
<i>Haw</i>	L	P. Cheung, R. Horowitz, R. T. Howe, "Design, Fabrication, Position Sensing, and Control of an Electrostatically-driven Polysilicon Microactuator," IEEE Transactions on Magnetics, Vol. 32, No. 1, January 1996, pages 122-128.					
<i>Haw</i>	M	M. Oda, M. Shirashi, "Mechanically Operated Optical Matrix Switch," Fujitsu Scientific and Technical Journal, September, 1981.					
<i>Haw</i>	N	E. K. Chan, R. W. Dutton, "Electrostatic Micromechanical Actuator with Extended Range of Travel," Journal of Microelectromechanical Systems, Volume: 9 Issue: 3 , Sept. 2000 Page(s): 321 -328					
<i>Haw</i>	O	Fedder et al., "Multimode Digital Control of a Suspended Polysilicon Microstructure", IEEE Journal of Microelectromechanical Systems, Vol. 5, No. 4, December 1996, pages 283-297					
<i>Haw</i>	P	Yun et al., "Surface Micromachined, Digitally force-Balanced Accelerometer with Integrated CMOS Detection Circuitry", Tech. Digest IEEE Solid-State Sensor and Actuator Workshop, June 1992, pages 126-131					
<i>Haw</i>	Q	Office Action dated 10/04/2002 in prior application 10/012,668					
<i>Haw</i>	R	Final Office Action dated 1/17/2003 in prior application 10/012,688					
EXAMINER <i>Edward R. Williams</i>			DATE CONSIDERED <i>22 Dec. 2004</i>				
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							